

# Resource Summary Report

Generated by [RRID](#) on Aug 5, 2026

## YXLON: FF70 CL X-Ray System

RRID:SCR\_020908

Type: Tool

### Proper Citation

YXLON: FF70 CL X-Ray System (RRID:SCR\_020908)

### Resource Information

**URL:** <https://www.yxlon.com/en/products/x-ray-and-ct-inspection-systems/yxlon-ff70-cl>

**Proper Citation:** YXLON: FF70 CL X-Ray System (RRID:SCR\_020908)

**Description:** X ray inspection system has been developed to enable automated analysis for flaws in semi-conductors. Flaws can be found on wafer, on substrate, in strip in sub assembly or in final device.

**Resource Type:** instrument resource

**Keywords:** YXLON, X-Ray System, Instrument Equipment, USEDit,

**Availability:** Commercially available

**Resource Name:** YXLON: FF70 CL X-Ray System

**Resource ID:** SCR\_020908

**Alternate IDs:** Model\_Number\_FF70

**Record Creation Time:** 20220129T080352+0000

**Record Last Update:** 20260801T190709+0000

### Ratings and Alerts

No rating or validation information has been found for YXLON: FF70 CL X-Ray System.

No alerts have been found for YXLON: FF70 CL X-Ray System.

### Data and Source Information

**Source:** [SciCrunch Registry](#)

## Usage and Citation Metrics

We have not found any literature mentions for this resource.